

IN THE CLAIMS

1. - 37. (Canceled)

38. (Currently Amended) A method for producing an electron-emitting device, the device comprising a conductive film including an electron emission region, the method comprising:

a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of the conductive film and solvent or dispersion medium is to be ejected; [[and]]

an ejecting step for ejecting the liquid by an ink jet apparatus to the position on the plane of the substrate detected by the first detection step[[,]]; and

an evaporating step for evaporating the solvent or dispersion medium contained in the liquid,

wherein the first detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

39. (Currently Amended) A method for producing an electronic device comprising:

a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of a material constituting the electronic

device and solvent or dispersion medium is to be ejected; [[and]]

an ejecting step for ejecting the liquid by an ink jet apparatus to the position on the plane of the substrate detected by the first detection step[[,.]]; and

an evaporating step for evaporating the solvent or dispersion medium contained in the liquid,

wherein the first detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

40. (Currently Amended) The method according to claim 38, wherein the ~~ejection of the ink~~ ejecting by the ink jet apparatus is performed while moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used in the first detection step.

41. (Currently Amended) The method according to claim 40, further comprising a second ~~detecting~~ detection step for detecting a condition ~~at least one predetermined attribute~~ of the liquid ejected by the ink jet apparatus.

42. (Previously Presented) The method according to claim 41, wherein the second detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the second

detection step.

43. (Currently Amended) The method according to claim 39, wherein the ~~ejection of the ink~~ the ejecting by the ink jet apparatus is performed while moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used in the first detection step.

44. (Currently Amended) The method according to claim 43, further comprising a second ~~detecting~~ detection step for detecting a condition ~~at least one~~ ~~predetermined attribute~~ of the liquid ejected by the ink jet apparatus.

45. (Currently Amended) The method according to claim 44, wherein the second detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the second detection step.

46. (New) A method for producing an electron-emitting device, the device comprising a conductive film including an electron emission region, the method comprising:

a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of the conductive film and solvent or

dispersion medium is to be ejected;

an ejecting step for ejecting the liquid by an ink jet apparatus to the position on the plane of the substrate detected by the first detection step; and

a film forming step for forming the conductive film on the substrate by heating the liquid,

wherein the first detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

47. (New) The method according to claim 46, wherein

the ejecting by the ink jet apparatus is performed while moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used in the first detection step.

48. (New) The method according to claim 47, further comprising a

second detection step for detecting a state of the liquid ejected by the ink jet apparatus.

49. (New) The method according to claim 48, wherein

the second detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the second detection step.

50. (New) A method for producing an electronic device comprising:  
a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of a material constituting the electronic device and solvent or dispersion medium is to be ejected;  
an ejecting step for ejecting the liquid by an ink jet apparatus to a position on the plane of the substrate detected by the first detection step; and  
a step for forming a member constituting an electronic device on the substrate by heating the liquid,  
wherein the first detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

51. (New) The method according to claim 50, wherein  
the ejecting by the ink jet apparatus is performed while moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used in the first detection step.

52. (New) The method according to claim 51, further comprising a second detection step for detecting a state of the liquid ejected by the ink jet apparatus.

53. (New) The method according to claim 52, wherein

the second detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the second detection step.

54. (New) A method for producing an electron-emitting device, the device comprising a conductive film including an electron emission region, the method comprising:

a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of the conductive film and solvent or dispersion medium is to be ejected;

an ejecting step for ejecting the liquid by an ink jet apparatus to the position on the plane of the substrate detected in the first detection step; and

an evaporating step for evaporating the solvent or dispersion medium contained in the liquid,

wherein the first detection step is performed by moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

55. (New) The method according to claim 54, wherein the ejecting by the ink jet apparatus is performed by moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used

in the first detection step.

56. (New) The method according to claim 55, further comprising a second detection step for detecting a state of the liquid ejected by the ink jet apparatus.

57. (New) The method according to claim 56, wherein  
the second detection step is performed by moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the second detection step.

58. (New) A method for producing an electronic device, comprising:  
a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of a material constituting the electronic device and solvent or dispersion medium is to be ejected; and

an ejecting step for ejecting the liquid by an ink jet apparatus to the position on the plane of the substrate detected by the first detection step; and

an evaporating step for evaporating the solvent or dispersion medium contained in the liquid,

wherein the first detection step is performed by moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

59. (New) The method according to claim 58, wherein  
the ejecting by the ink jet apparatus is performed by moving,  
relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used  
in the first detection step.

60. (New) The method according to claim 59, further comprising a  
second detection step for detecting a state of the liquid ejected by the ink jet apparatus.

61. (New) The method according to claim 60, wherein  
the second detection step is performed by moving, relatively to the  
substrate, both of an ejector of the ink jet apparatus and a detector used in the second  
detection step.

62. (New) A method for producing an electron-emitting device, the  
device comprising a conductive film including an electron emission region, the method  
comprising:

a first detection step for detecting a position on a plane of a  
substrate, to which a liquid containing an element of the conductive film and solvent or  
dispersion medium is to be ejected; and

an ejecting step for ejecting the liquid by an ink jet apparatus to the



position on the plane of the substrate detected in the first detection step; and

a film forming step for forming the conductive film on the substrate by heating the liquid,

wherein the first detection step is performed by moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

63. (New) The method according to claim 62, wherein the ejecting by the ink jet apparatus is performed by moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used in the first detection step.

64. (New) The method according to claim 63, further comprising a second detection step for detecting a state of the liquid ejected by the ink jet apparatus.

65. (New) The method according to claim 64, wherein the second detection step is performed by moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the second detection step.

66. (New) A method for producing an electronic device, comprising:

a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of a material constituting the electronic device and solvent or dispersion medium is to be ejected;

an ejecting step for ejecting the liquid by an ink jet apparatus to the position on the plane of the substrate detected by the first detection step; and

a step for forming a member constituting an electronic device on the substrate by heating the liquid,

wherein the first detection step is performed by moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

67. (New) The method according to claim 66, wherein the ejecting by the ink jet apparatus is performed by moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used in the first detection step.

68. (New) The method according to claim 67, further comprising a second detection step for detecting a state of the liquid ejected by the ink jet apparatus.

69. (New) The method according to claim 68, wherein the second detection step is performed by moving, relatively to the

substrate, both of an ejector of the ink jet apparatus and a detector used in the second detection step.